

EAST Search History

EAST Search History (Prior Art)

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L3	2	((correct\$4 or rectify \$4) with (photo or optical) with effect) same ((different or distinct or separate) near3 (area or section or layer or pattern)) and (mos near3 gate)	US-PGPUB; USPAT; USOCR	OR	ON	2009/08/28 18:37
L4	2	((correct\$4 or rectify \$4) with (photo or optical) with effect) same ((edge or corner) with (separat \$4 or divid\$4) with (multiple or plurality))	US-PGPUB; USPAT; USOCR	OR	ON	2009/08/28 19:03
L5	59	((correct\$4 or rectify \$4) with (photo or optical) with effect) and ((edge or corner) with (separat\$4 or divid\$4) with (multiple or plurality))	US-PGPUB; USPAT; USOCR	OR	ON	2009/08/28 19:03
S29	4	"6174633"	US-PGPUB; USPAT; USOCR	OR	ON	2009/08/27 18:28
S30	147	((wafer or semiconductor) with (correct\$4) with (photo or optical) with effect) and (((first same second) or (multiple or plurality)) with (layer or level))	US-PGPUB; USPAT; USOCR	OR	ON	2009/08/27 18:38

S31	5	((wafer or semiconductor) with (correct\$4) with (photo or optical) with effect) and (((first same second) or (multiple or plurality)) with (layer or level)) same (standard or threshold)	US-PGPUB; USPAT; USOCR	OR	ON	2009/08/27 18:38
S32	6	((wafer or semiconductor or reticle) with (correct \$4) with (photo or optical) with effect) and (((first same second) or (multiple or plurality)) with (layer or level)) same (standard or threshold)	US-PGPUB; USPAT; USOCR	OR	ON	2009/08/27 18:40
S33	38	((wafer or semiconductor or reticle) with (correct \$4) with (photo or optical) with effect) and (((first same second) or (multiple or plurality)) with (layer or level)) and ((different or distinct or separate) with (area or section))	US-PGPUB; USPAT; USOCR	OR	ON	2009/08/27 18:42
S34	496	((correct\$4) with (photo or optical) with effect) and (((first same second) or (multiple or plurality)) with (layer or level)) and ((different or distinct or separate) with (area or section))	US-PGPUB; USPAT; USOCR	OR	ON	2009/08/27 18:49

S35	380	((correct\$4) with (photo or optical) with effect) and (((first same second) or (multiple or plurality)) with (layer or level)) and ((different or distinct or separate) with (area or section)) and (wafer or semiconductor or reticle or mask)	US-PGPUB; USPAT; USOCR	OR	ON	2009/08/27 18:50
S36	219	((correct\$4) with (photo or optical) with effect) and (((first same second) or (multiple or plurality)) with (layer or level)) same (wafer or semiconductor or reticle or mask) and ((different or distinct or separate) with (area or section))	US-PGPUB; USPAT; USOCR	OR	ON	2009/08/27 18:50
S37	18	((correct\$4) with (photo or optical) with effect) same ((different or distinct or separate) near3 (area or section or layer)) same (wafer or semiconductor or reticle or mask)	US-PGPUB; USPAT; USOCR	OR	ON	2009/08/27 19:16

EAST Search History (Interference)

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8/ 28/ 2009 7:54:14 PM**C:\ Documents and Settings\ Epark\ My Documents\ EAST\ Workspaces\ 10-813834****Method and Program for Correcting and Testing mask Pattern optical proximity effect.****wsp**